

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of  
Takamitsu HIGUCHI et al.

Attn: OFFICE OF PUBLICATIONS

Notice of Allowance  
Mailed: 01/11/2005

Batch No.: 6923

Application No.: 10/644,989

Group Art Unit: 2818

Filed: August 21, 2003

Examiner: D. Vu

Docket No.: 116916

For: SUBSTRATE FOR ELECTRONIC DEVICES, MANUFACTURING METHOD THEREOF,  
AND ELECTRONIC DEVICE

**REQUEST FOR ACKNOWLEDGMENT OF  
CONSIDERATION OF DISCLOSED INFORMATION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

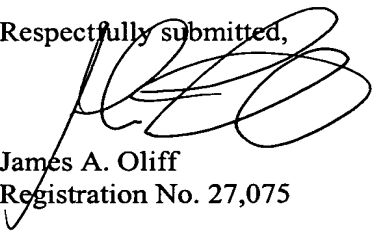
Sir:

An Information Disclosure Statement with Form PTO-1449 was filed in the above-captioned patent application on February 11, 2005. Applicants have not yet received back from the Examiner a copy of the Form PTO-1449 initialed to acknowledge the fact that the Examiner has considered the cited disclosed information.

The Examiner is requested to initial and return to the undersigned a copy of the subject Form PTO-1449. For the convenience of the Examiner, a copy of that form is attached.

Should there be any questions concerning this communication, please telephone the undersigned at the number set forth below.

Respectfully submitted,

  
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JAO:JWF/ldg  
Date: March 31, 2005

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**DEPOSIT ACCOUNT USE  
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Sheet 1 of 1

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 116916		APPLICATION NO. 10/644,989	
INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)				APPLICANT(S) Takamitsu HIGUCHI et al.			
				FILING DATE August 21, 2003		GROUP 2818	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	A	Pignolet A., et al., "Large Area Pulsed Laser Deposition of Aurivillius-type Layered Perovskite Thin Films", Ferroelectrics, Overseas Publishers Associations, Amsterdam, NL, , Vol. 202, No. 1-4, 1997, pp. 285-298.					
	B	Mechin L. et al., "A combined x-ray specular reflectivity and spectroscopic ellipsometry study of CeO <sub>2</sub> /yttria-stabilized-zirconia bilayers on Si(100) substrates", Journal of Applied Physics, American Institute of Physics, New York, US, Vol. 84, No. 9, 1 November 1998, pp. 4935-4940.					
	C	Matthee T., et al., "Orientation relationships of epitaxial oxide buffer layers on silicon (100) for high-temperature superconducting Yba2Cu307-x films", Applied Physics Letters USA, Vol. 61, No. 10, 7 September 1992, pp. 1240-1242.					
EXAMINER					DATE CONSIDERED		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Date: February 11, 2005